DOCKET: CU-2636 PATENT

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Sang Ick LEE et al.

Serial No.: 09/994,284

Filed: 26 November 2001

For: METHOD OF FORMING METAL

GATE IN SEMICONDUCTOR

**DEVICE** 

Group Art Unit: 2823

Examiner: Pham, Thanh V.

AMENDMENT AFTER FINAL

1-30-03 1-4/03 Velva

## Certification under 37 C.F.R. §1.8(a)

I hereby certify that this correspondence, and all documents referred to herein as being attached, are being transmitted by facsimile to the United States Patent and Trademark Office at the following facsimile number: (703) 308-7382, to the attention of Examiner Pham, and addressed to the Commissioner for Patents, Washington, D.C. 20231 on January 15, 2003.

Commissioner for Patents Washington, D.C. 20231

## AMENDMENT UNDER 37 C.F.R. § 1.116

In further response to the Office Action dated October 15, 2002, please amend the above captioned application for patent as follows:

## IN THE CLAIMS:

Please substitute the following amended Claim 1 for pending Claim 1. A marked up copy of the claims showing the amendments to the amended claims only are attached hereto.

Please cancel Claims 4 and 7, without prejudice.

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